1	8	7		6		5		4	I	3	
D	 NOTES CONTINUED: 4. ALL MACHINING FLUIDS MU AND FREE OF SULFUR, SILICO SCRIBE, ENGRAVE, OR MEC PART NUMBER, REVISION (A SURFACE OF PART FOLLOW NUMBER. SERIAL NUMBERS S CONSECUTIVELY. USE MININ THE PART DICTATES SMALLEI EXAMPLE DXXXXXX-VY, TYI 6. APPROXIMATE WEIGHT = 0.5 7. MACHINE ALL SURFACES TO REMOVAL TECHNIQUES (INC IS NOT ALLOWED. USE OF SOC 8. ALL PARTS SHALL BE MANUF SPECIFICATION E0900364. 9. ALL MATERIAL IS TO BE VIRG APPROVED IN ADVANCE A 10. NO REPAIRS SHALL BE MADIF BY LIGO LABORATORY. IN G ARE NEVER ACCEPTABLE. TH CIRCUMSTANCES CAN BE R LIGO CONTRACTING OFFIC REVIEW BOARD (MRB) PROCE 	DNE AND CHLORINE. HANICALLY STAMP (NO ND VARIANT OR "TYPE" I ED ON THE NEXT LINE WI START AT 001 FOR THE FIR 10M 0.12 HIGH CHARAC R CHARACTERS. A VIBRA PE-XX, S/N XXX. 5 LB.=.25 KG. 9 REMOVE OXIDES AND CLUDING SANDING OR S COTCH-BRITE OR SIMILAI GOTCH-BRITE OR SIMILAI ACTURED IN ACCORDA SIN MATERIAL (I.E. NOT W ND IN WRITING BY LIGO, E UNLESS APPROVED IN SENERAL WELD REPAIRS HE MATERIAL USED MUST REVIEWED IF AND WHEN SER'S REPRESENTATIVE (C	INKS OR DYES APPLICABLE TH A THREE DI ST ARTICLE AI TERS, UNLESS TORY TOOL N VILL FINISH, US COURING FC PRODUCTS I NCE WITH LIG YELD REPAIRS REFER TO LIG ADVANCE, AI AND PRESS FIT BE VIRGIN M. BROUGHT TO OTR) THROUG	5) DRAWING ON NOTED IGIT SERIAL ND PROCEED THE SIZE OF MAY BE USED. SE OF ABRASIVE OR MATTE FINISH) S FORBIDDEN. GO OR PLUGS) UNLE GO-E0900364. ND IN WRITING, INSERT REPAIRS ATERIAL. SPECIAL THE ATTENTION O	_ DF		.14			OVES 4.88	E
C				I				12	.450		
D1003168 TRIM MASS .25 KG, aLIGO BSC-ISI, PART PDM REV: X-003, DRAWING PDM REV: X-003		2 2X .75 2X 1.50	.355			0 — 1.000 — 1.500 — 2.000 —	(45.0°	· 22		2X Ø .406 T	HRU A
GO BSC-			.005	.00	5						5.900
1003168 TRIM MASS .25 KG, allt P				TOLE .XX .XXX	ENSIONS ARE IN INCHES RANCES: ±.015 ±.005 SULAR±.5°	1. INTERPF 2. REMOV	<u>s: (unless otherwise specif</u> Ret Drawing per /e All Sharp EDG T SCALE FROM DF 6061-T6 AI	ASME Y14.5- SES, .03 x 45°. RAWING.	10-32 UNF	9 THRU ALL THRU ALL ALIFORNIA INSTITUTE OF TECH ASSACHUSETTS INSTITUTE OF NCED LIGO	inology technology jb-system SEI
	8	7		6	I	5		4	r	3	I

